



Fig. 2

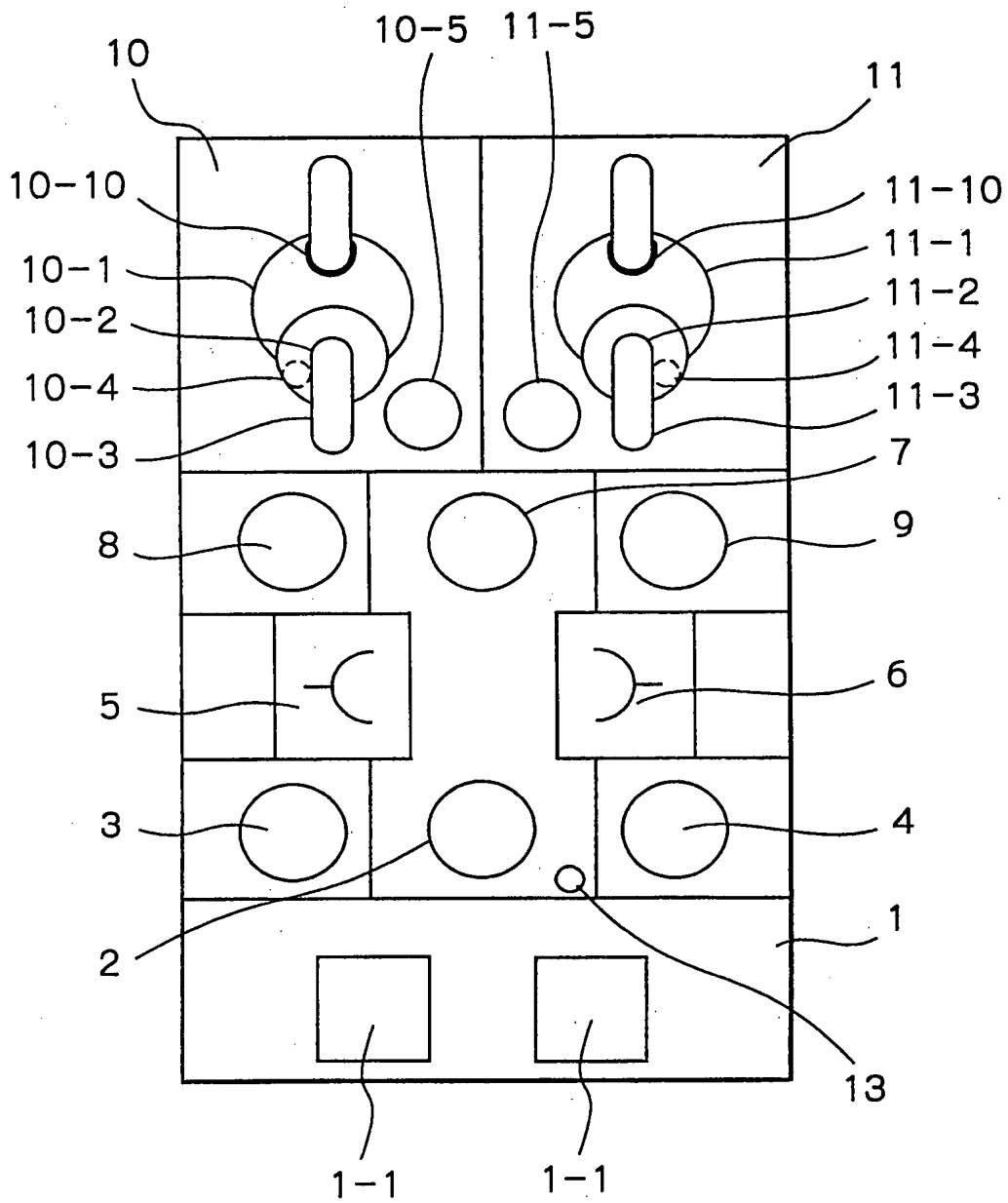


Fig. 3

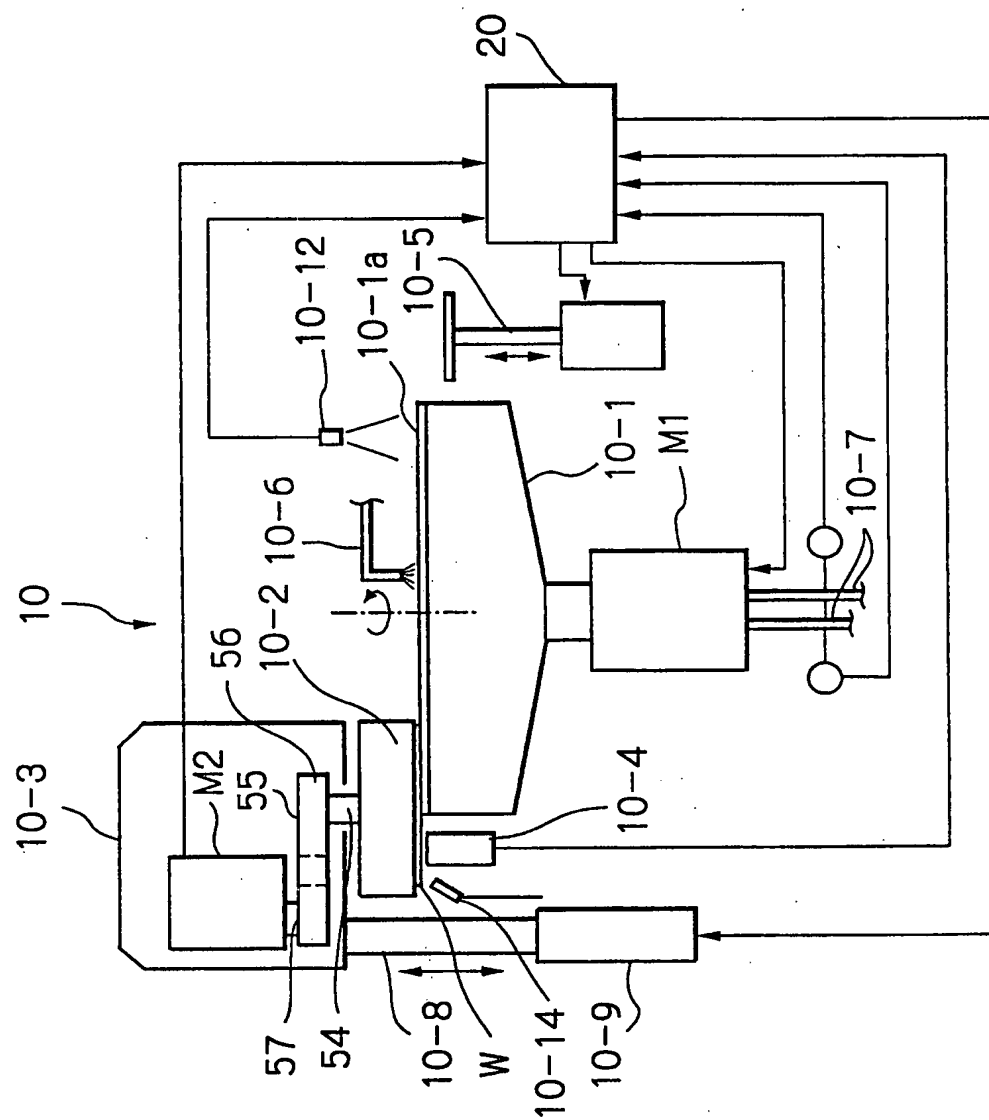


Fig. 4

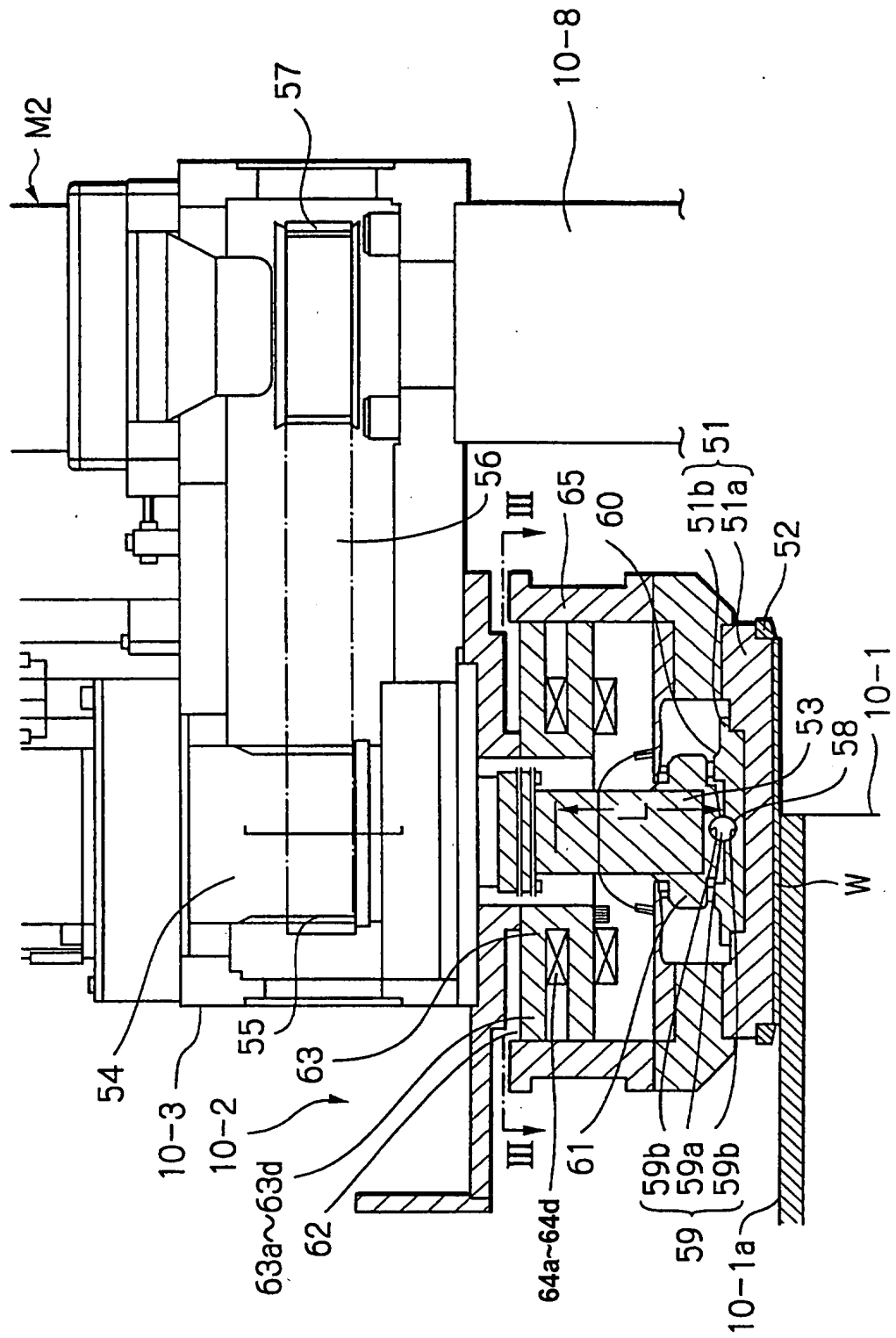


Fig. 5

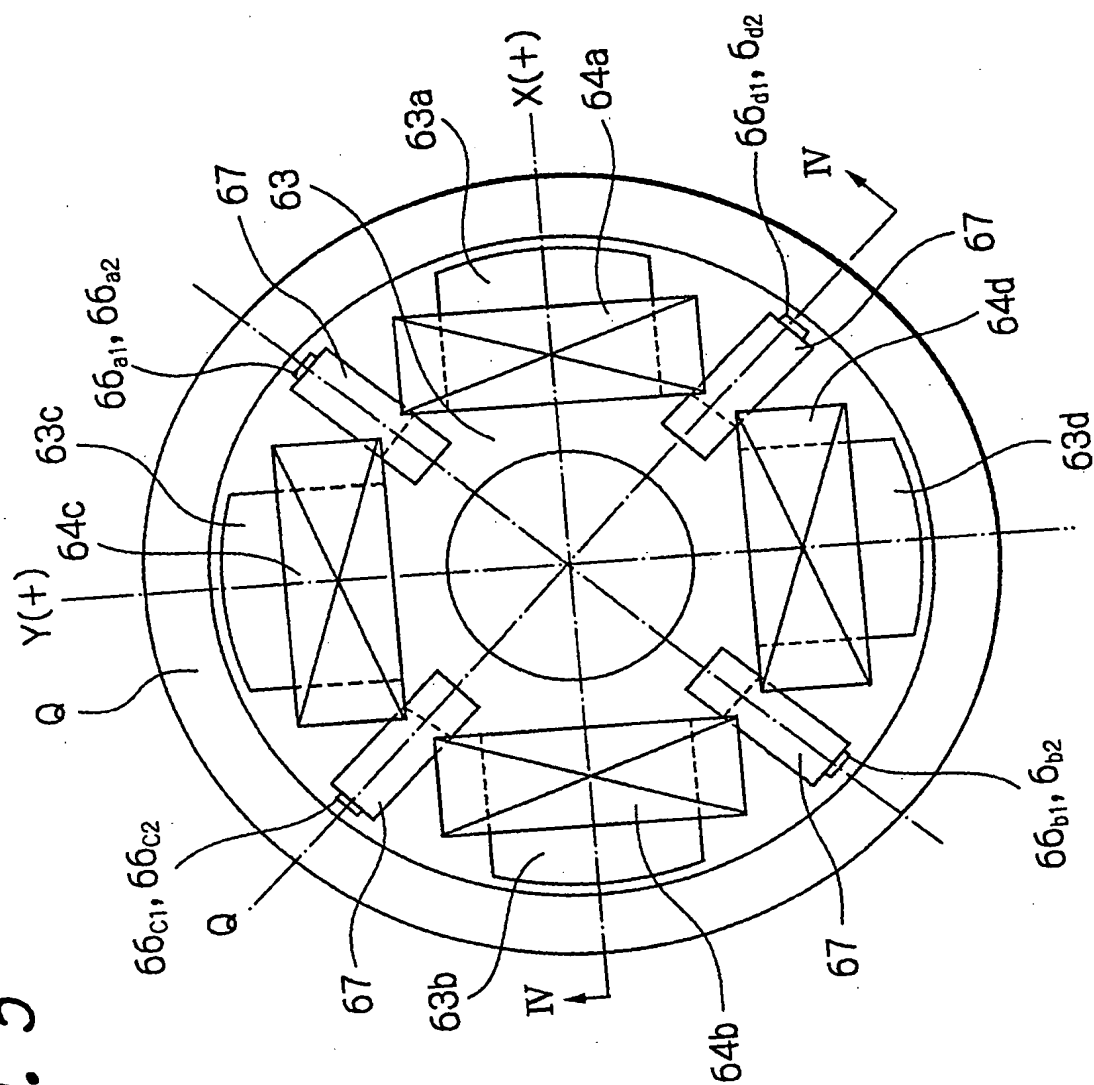


Fig. 6

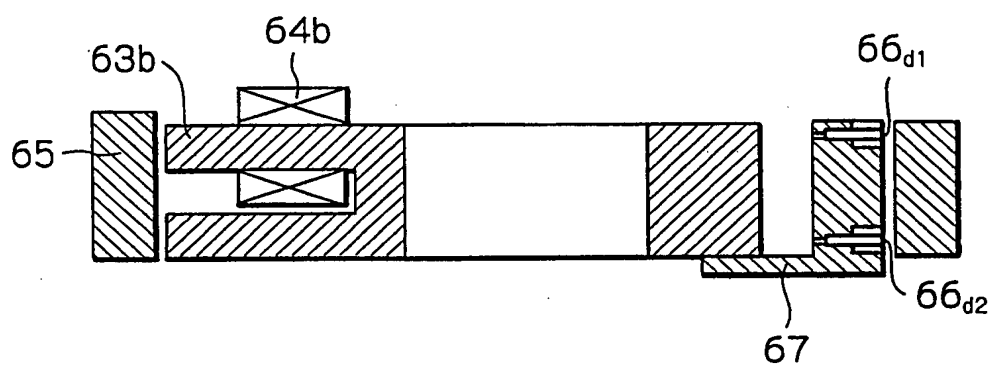


Fig. 7

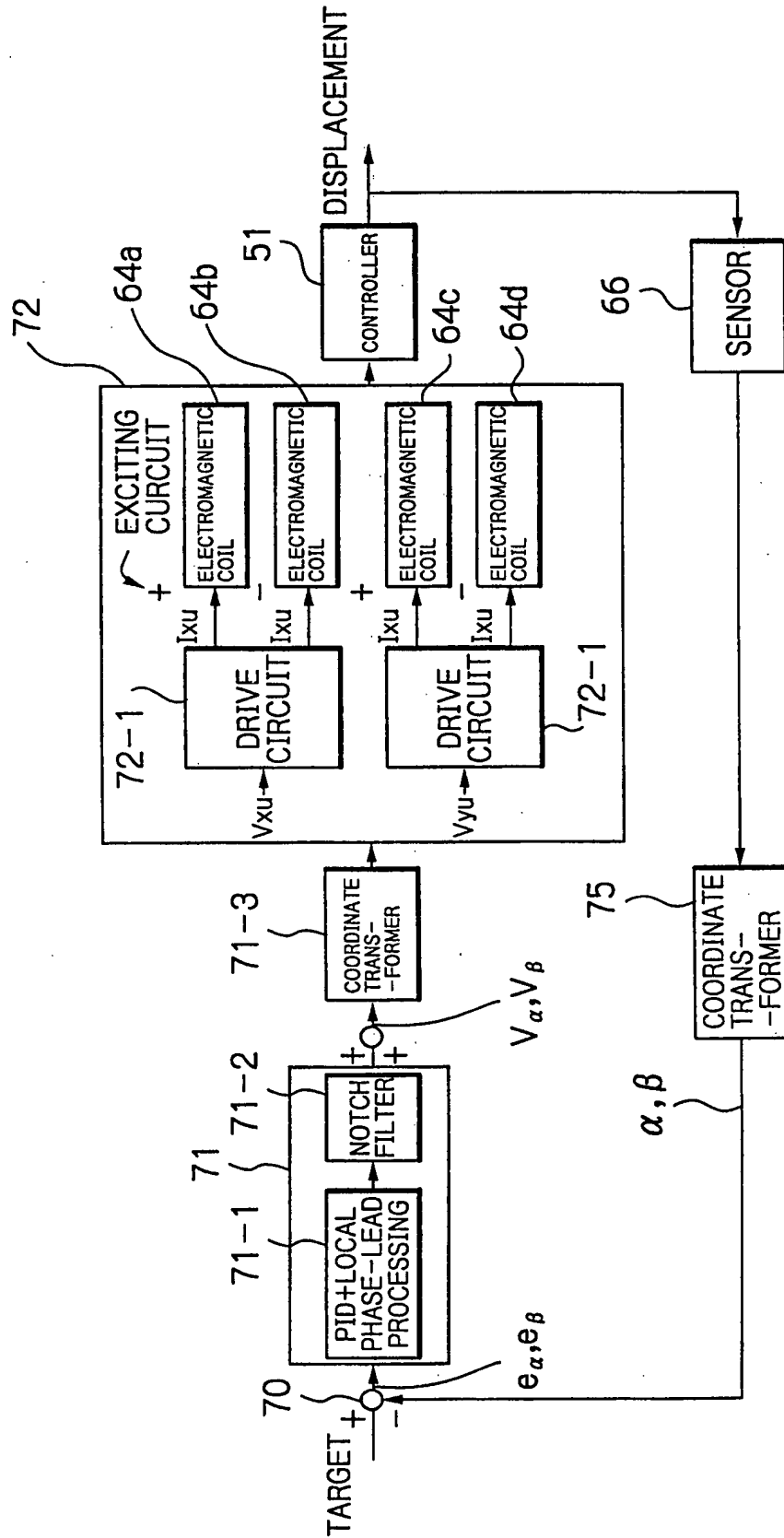


Fig. 8

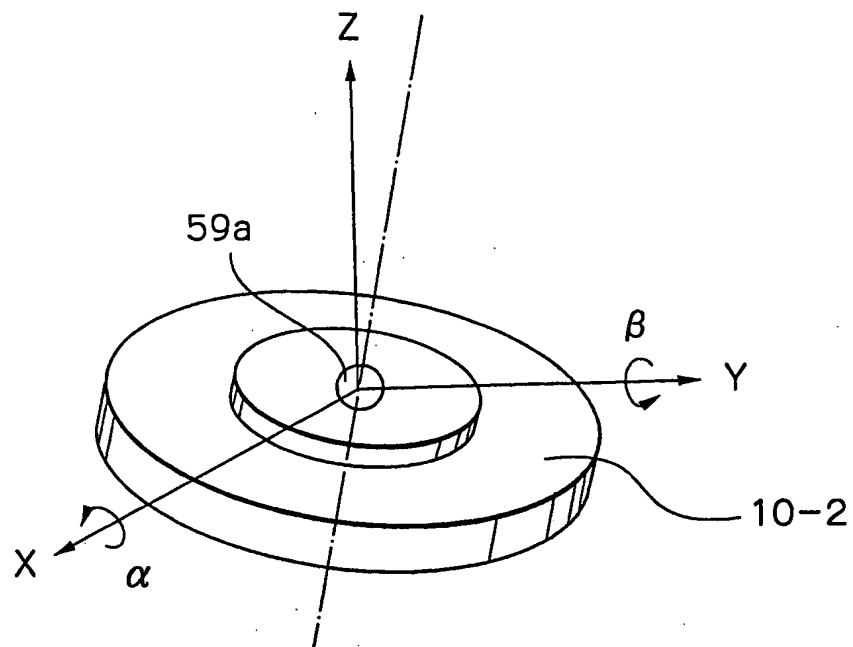


Fig. 9

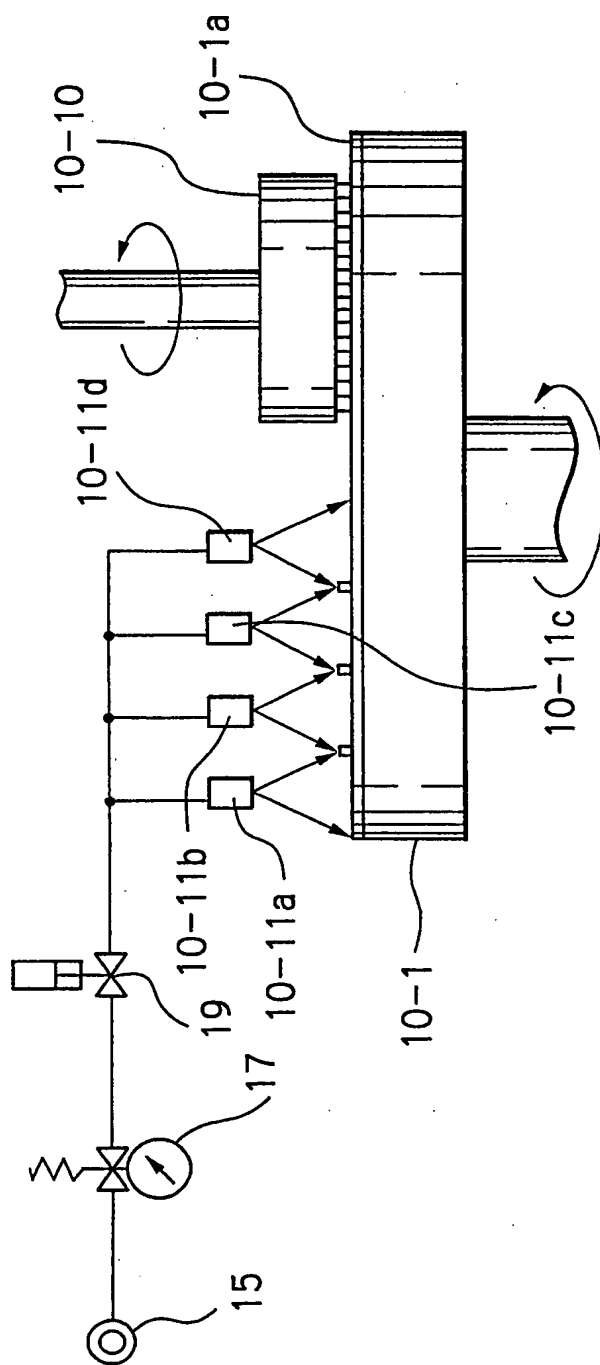


Fig. 11

	SLURRY	SUBSTRATE URGING FORCE	NUMBER OF REVOLUTIONS
FIRST POLISHING STEP ↓	SILICA BASE SLURRY FOR COPPER POLISHING	400 g/cm ²	70 rpm
SECOND POLISHING STEP ↓	SILICA BASE SLURRY FOR COPPER POLISHING	200 g/cm ²	70 rpm
END POINT ↓			
POLISHING SURFACE CLEANING ↓			
THIRD POLISHING STEP	SILICA BASE SLURRY FOR Ta POLISHING	200 g/cm ²	50 rpm

Fig. 12

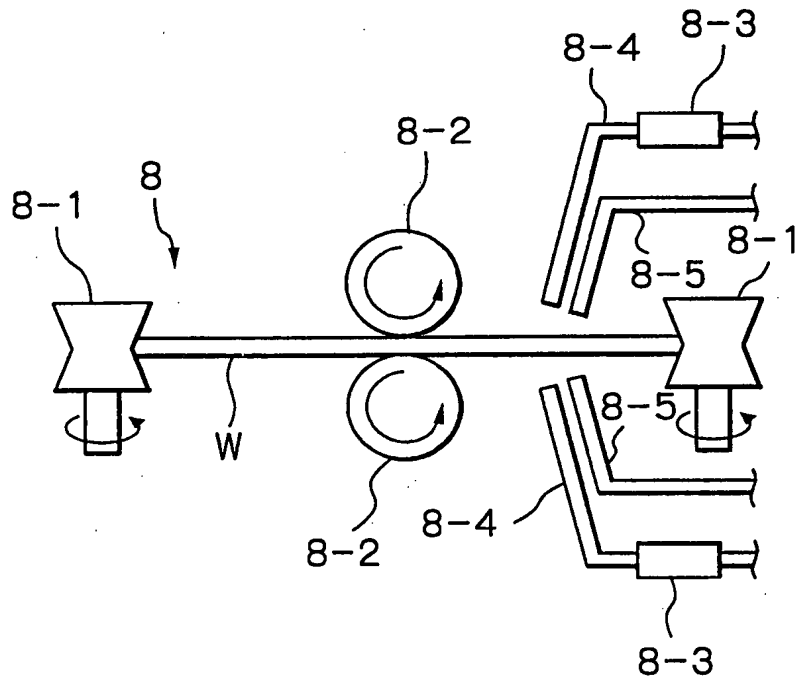


Fig. 13

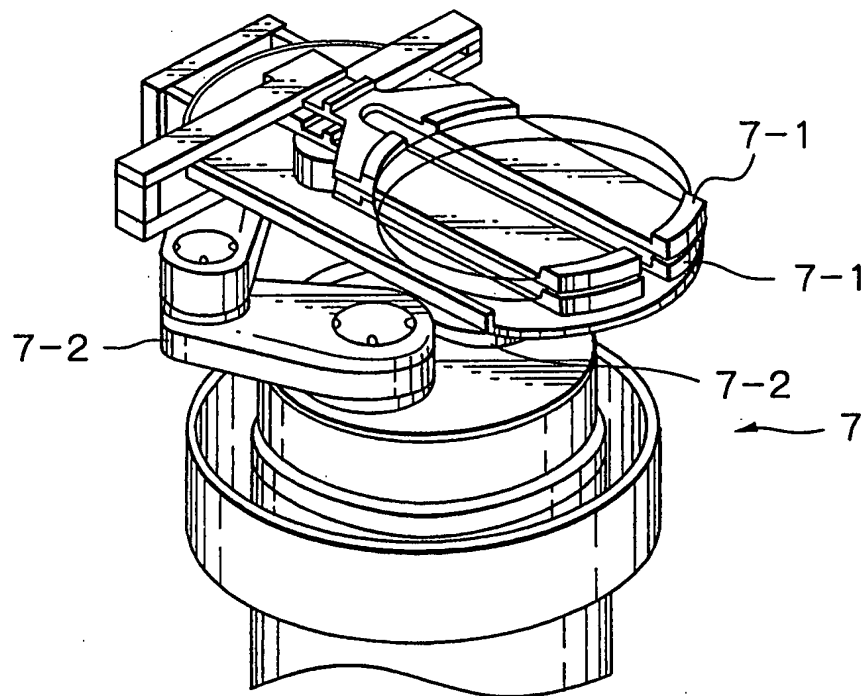


Fig. 14

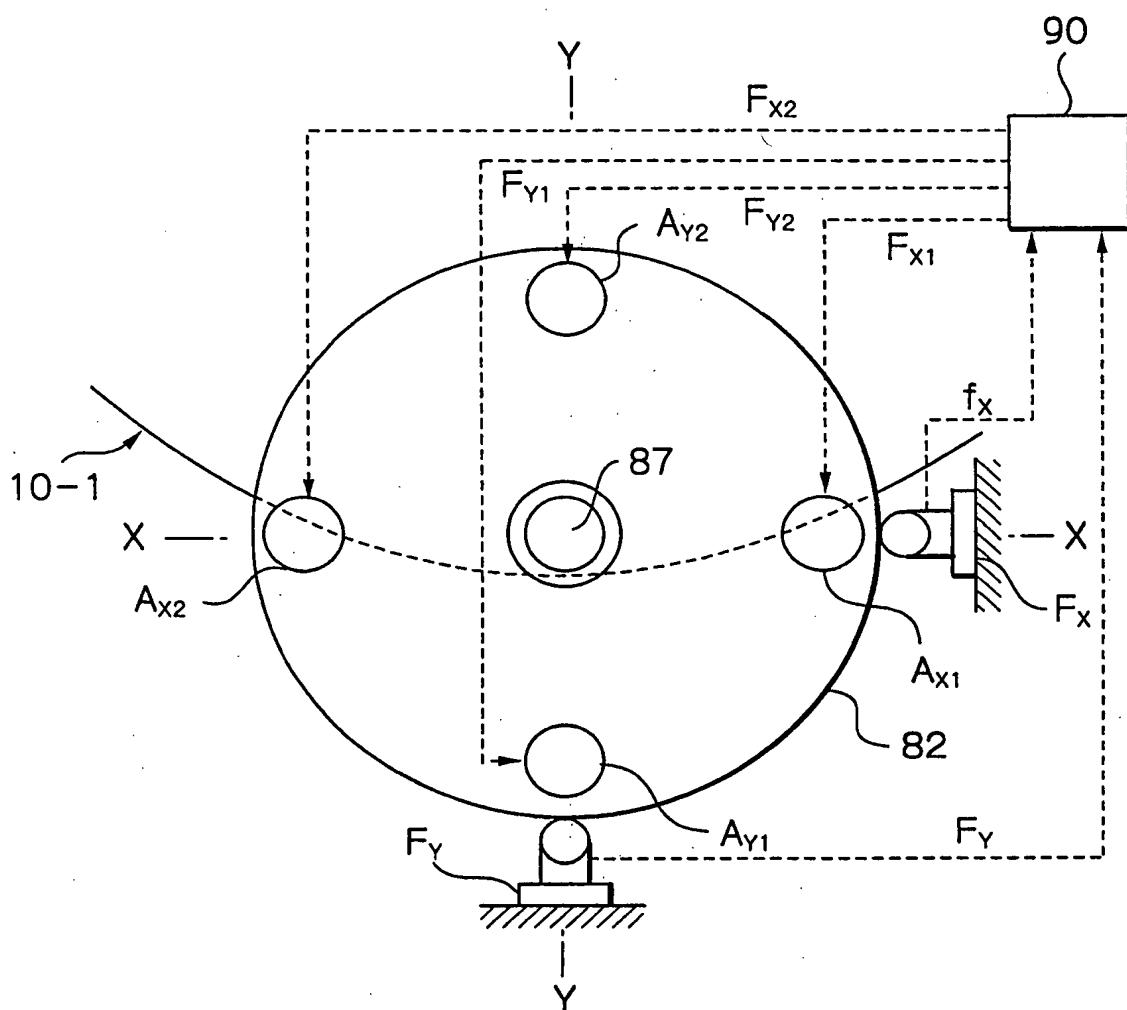


Fig. 15

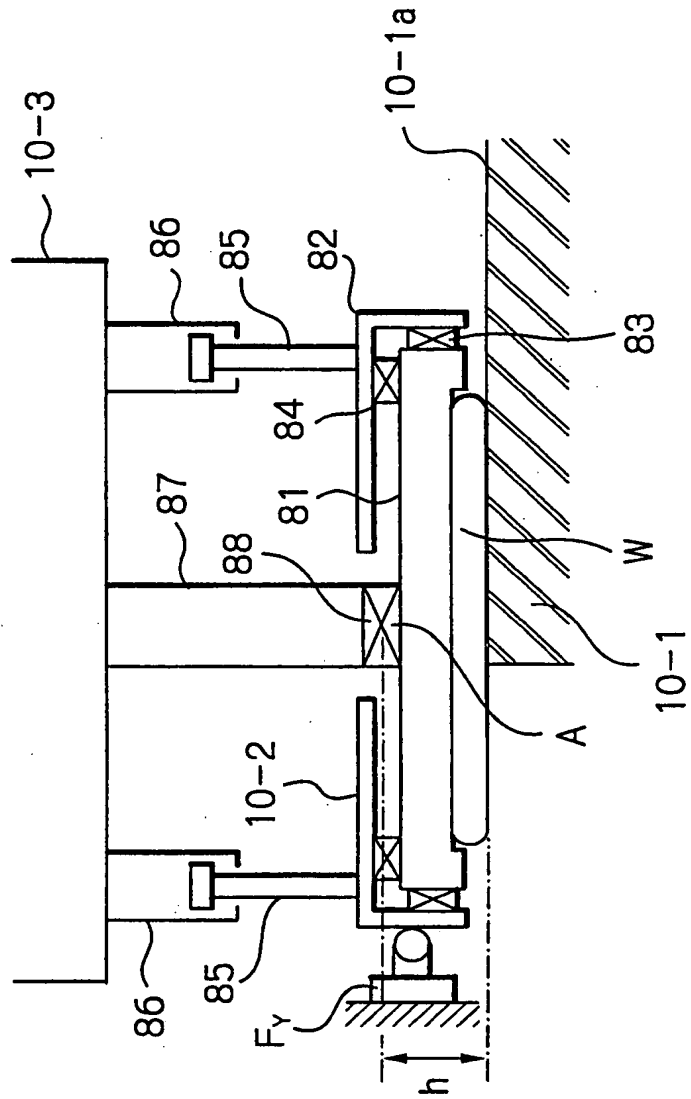


Fig. 16

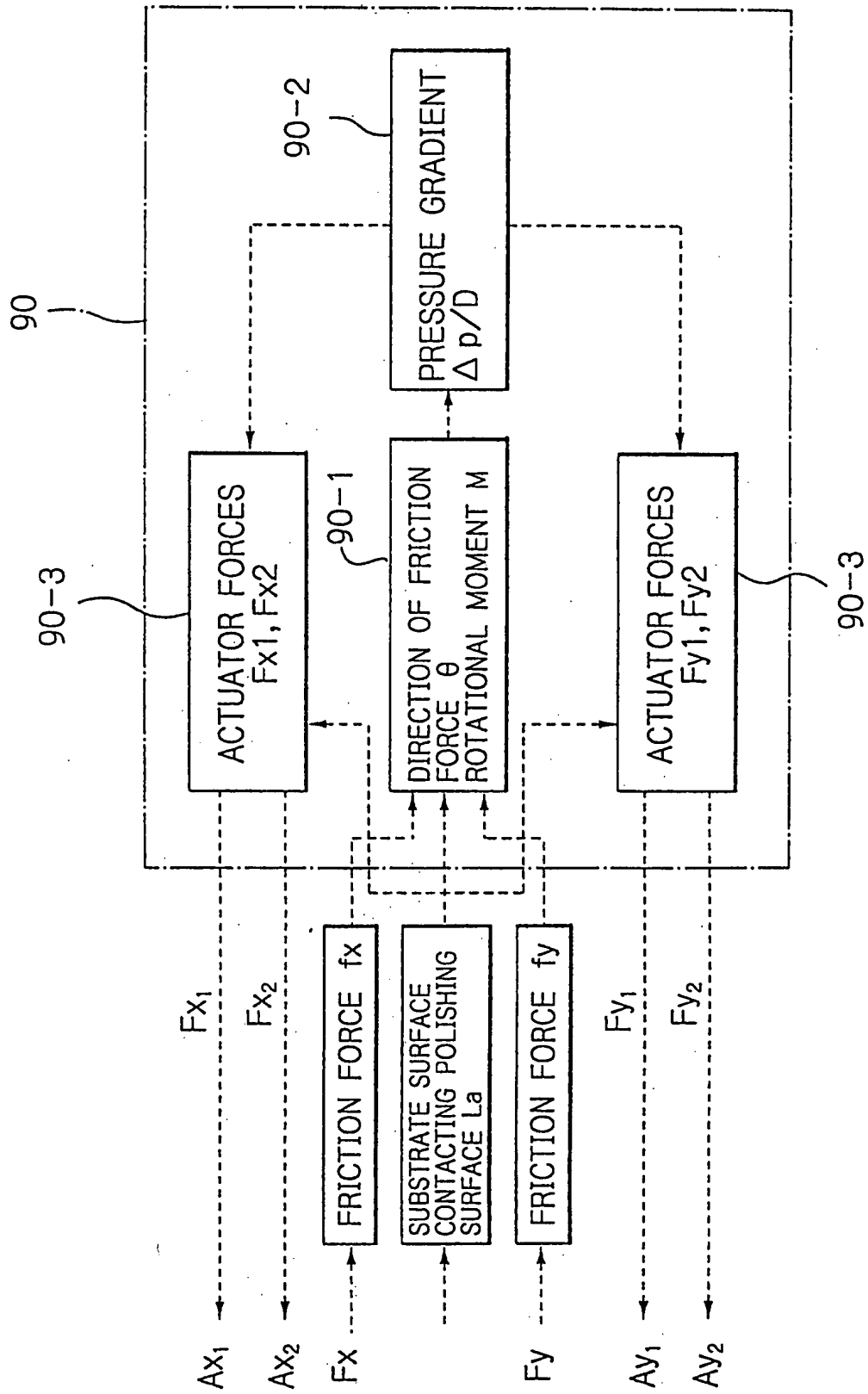


Fig. 17

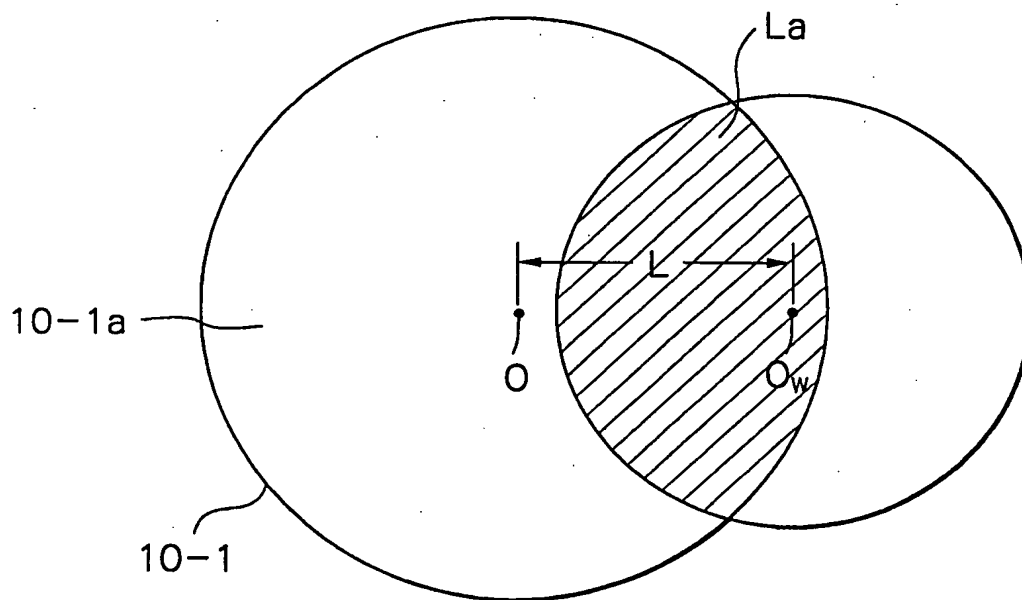


Fig. 18

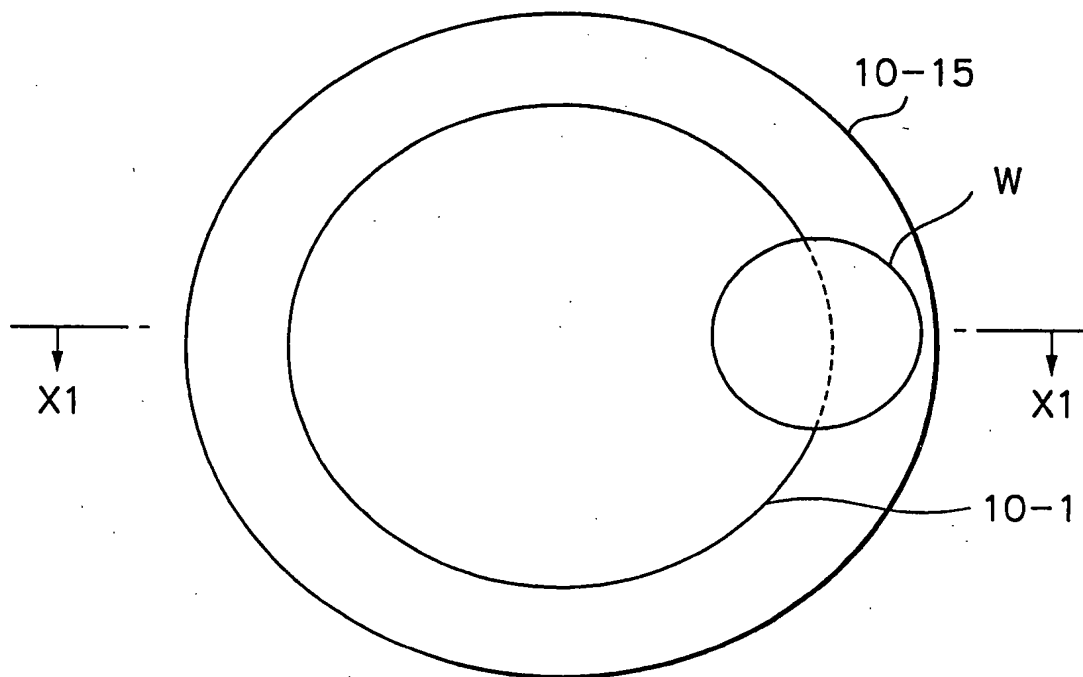


Fig. 19

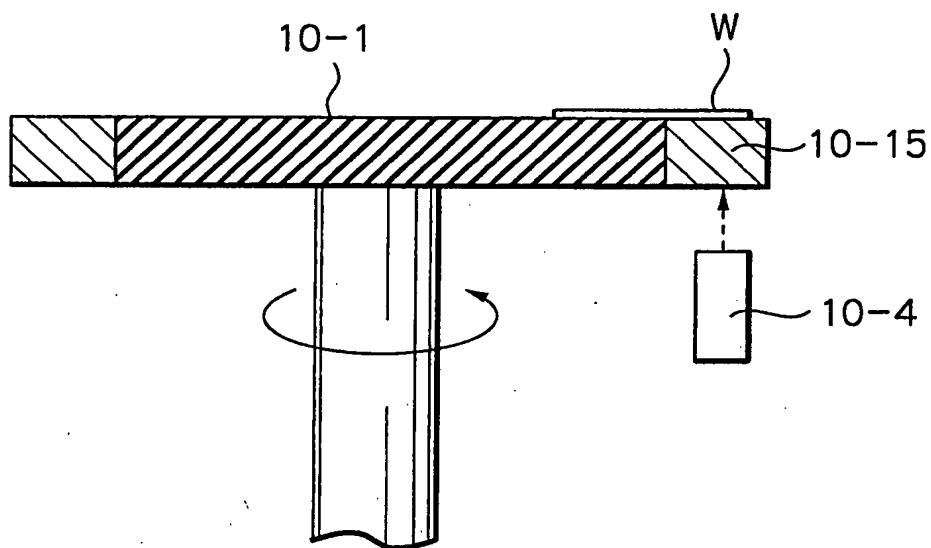


Fig. 20

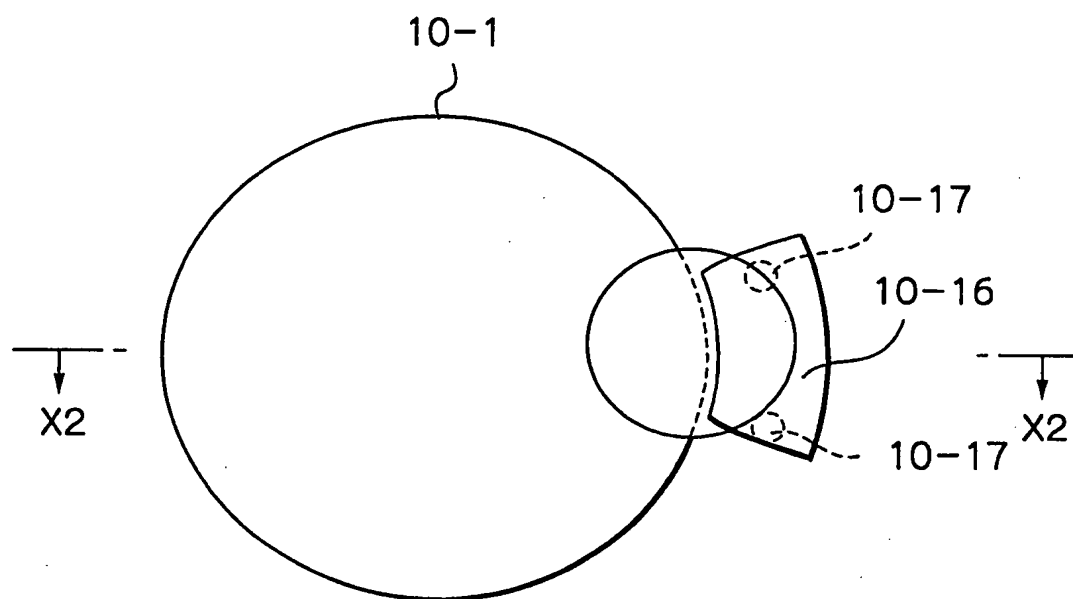


Fig. 21

